



520.34403CV4

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): T. MASUDA, et al
Serial No.: 09/421,043
Filed: October 20, 1999
For: PLASMA ETCHING APPARATUS AND PLASMA ETCHING
METHOD
Group: 1763
Examiner: A. Mulero

AMENDMENT

Mail Stop: AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

December 27, 2005

Sir:

The following amendments and remarks are respectfully submitted in connection with the RCE of the above-identified application in response to the Office Action dated July 26, 2005.

Amendment of the Claims; and

Remarks are included following the amendments.